AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions and listings of claims in the aboveidentified application:

- 1. (currently amended) A component, comprising:
 - a silicon-based substrate: and
- a diffusion barrier coating disposed on said substrate, wherein said diffusion barrier coating comprises:
 - a first isolation layer disposed on said silicon-based substrate;
 - a first oxygen barrier layer disposed on said first isolation layer; and
 - a second isolation layer disposed on said first oxygen barrier layer,
 - wherein said first oxygen barrier layer comprises a SiO₂-based material,
 - wherein said first isolation layer comprises a material selected from the

group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, Mo₅Si₃, Si₃N₄, Si₂N₂O, and SiC; and

wherein said second isolation layer comprises a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, and Mo₅Si₃; and

an environmental barrier coating disposed on said diffusion barrier coating

- (original) The component of claim 1, further comprising:
 a second oxygen barrier layer disposed on said second isolation layer; and
 a third isolation layer disposed on said second oxygen barrier layer.
- (canceled).
- (currently amended) The component of claim [[3]]L, wherein said environmental barrier coating comprises at least one oxide of an element selected from the group

consisting of Ta, Al, Cr, Hf, Ti, Zr, Mo, Nb, Ni, Sr, Mg, Si, and the rare earth elements including Sc, Y, and the lanthanide series of elements.

Appl. No. 10/644,523 Reply to Office Action of February 7, 2007

- (original) The component of claim 4, wherein said environmental barrier coating comprises at least about 50 mole % AITaO₄.
 - (currently amended) The component of claim [[3]]1, further comprising:
 a thermal barrier coating disposed on said environmental barrier coating.
- (original) The component of claim 1, wherein said first oxygen barrier layer comprises a material selected from the group consisting of a silicate glass and crystalline silica.
- 8. (original) The component of claim 1, wherein said first oxygen barrier layer comprises silica and at least one oxide of an element selected from the group consisting of Ta, Al, Cr, Hf, Ti, Zr, Mo, Nb, Ni, Sr, Mg, Si, and the rare earth elements including Sc, Y, and the lanthanide series of elements.
- (original) The component of claim 1, wherein said first isolation layer and said second isolation layer have the same composition.
- (original) The component of claim 1, wherein:
 said first isolation layer consists essentially of silicon nitride;
 said second isolation layer consists essentially of Ta₂O₅; and
 said first oxygen barrier layer is formed in situ by reaction of said silicon nitride
 with said Ta₂O₅.
- 11. (original) The component of claim 1, wherein said first oxygen barrier layer has a thickness in the range of from about 1 to 20 microns.
- (original) The component of claim 1, wherein said first and second isolation layers each have a thickness in the range of from about 1 to 100 microns.
 - 13. (previously presented) A component, comprising:

a silicon-based substrate; and

a diffusion barrier coating disposed on said substrate, wherein said diffusion barrier coating comprises:

- a first isolation layer disposed on said silicon-based substrate;
- a first oxygen barrier layer disposed on said first isolation layer;
- a second isolation layer disposed on said first oxygen barrier layer; and an environmental barrier coating disposed on said diffusion barrier

coating,

wherein said first oxygen barrier layer provides a barrier to the diffusion of oxygen therethrough,

wherein said first isolation layer comprises a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, Mo₅Si₃, Si₃N₄, Si₂N₂O, and SiC; and wherein said second isolation layer consists essentially of Ta₂O₅.

- (original) The component of claim 13, further comprising a thermal barrier coating disposed on said environmental barrier coating, and wherein said environmental barrier coating comprises AlTaO₄ or Ta₂O₅.
- (original) The component of claim 13, wherein said thermal barrier coating comprises yttria stabilized zirconia or yttria stabilized hafnia.
 - (previously presented) A component, comprising:
 - a silicon-based substrate;
- a first isolation layer disposed on said silicon-based substrate, wherein said first isolation layer comprises a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, Mo₅Si₃, Si₃N₄, Si₂N₂O, and SiC;
- a first oxygen barrier layer disposed on said first isolation layer, wherein said first oxygen barrier layer comprises a material selected from the group consisting of a silicate glass, and crystalline silica; and

a second isolation layer disposed on said first oxygen barrier layer, wherein said second isolation layer comprises a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, and Mo·Si₃,

wherein said first oxygen barrier layer has a thickness in the range of from about 1 to 20 micron, and

wherein said first and second isolation layers each have a thickness in the range of from about 1 to 100 micron.

17. (currently amended) A component, comprising:

- a silicon-based substrate; and
- a diffusion barrier coating disposed on said substrate, wherein said diffusion barrier coating comprises:
 - a plurality of isolation layers, at least one of said plurality of isolation layers disposed on said silicon-based substrate; and

one or more oxygen barrier layers, each of said one or more oxygen barrier layers disposed between two of said plurality of isolation layers; wherein

each of said one or more oxygen barrier layers comprises a $\rm SiO_2\textsc{-}$ based material, and

at least one of said plurality of isolation layers consists essentially of $Ta_2\mathrm{O}_{5\underline{i}}$ and

an environmental barrier coating disposed on said diffusion barrier coating

- 18. (original) The component of claim 17, wherein: said one or more oxygen barrier layers consist of n oxygen barrier layers, and said plurality of isolation layers consist of (n+1) isolation layers, wherein n is an integer in the range of from 1 to 5.
 - (previously presented)A component, comprising:
 a gas turbine engine element including a silicon-based substrate; and

Appl. No. 10/644,523 Reply to Office Action of February 7, 2007

a diffusion barrier coating disposed on said substrate, wherein said diffusion barrier coating comprises:

- a first isolation layer disposed on said silicon-based substrate;
- a first oxygen barrier layer disposed on said first isolation layer;
- a second isolation layer disposed on said first oxygen barrier layer; and an environmental barrier coating disposed on said second isolation layer

and comprising at least about 50 mole % AlTaO₄, and further comprising at least one oxide of an element selected from the group consisting of Ta, Al, Cr, Hf, Ti, Zr, Mo, Nb, Ni, Sr, Mg, Si, and rare earth elements including lanthanide series elements,

wherein said first oxygen barrier layer serves as a barrier to the diffusion of oxygen therethrough,

wherein said first isolation layer is inert to said silicon-based substrate,

and

coating.

wherein said second isolation layer is inert to said environmental barrier

- (currently amended) A diffusion barrier coating for a silicon-based substrate, comprising:
 - a first isolation layer;
 - a first oxygen barrier layer disposed on said first isolation layer; and
 - a second isolation layer disposed on said first oxygen barrier layer,
 - wherein said first oxygen barrier layer comprises a SiO2-based material, and
 - wherein each of said first isolation layer and said second isolation layer comprises
- a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, and Mo₅Si₃,

wherein said first oxygen barrier layer has a thickness in the range of from about

1 to 20 microns, and

wherein said first and second isolation layers each have a thickness in the range of from about 1 to 100 microns.

 (original) The diffusion barrier coating of claim 20, wherein said first isolation layer is disposed on said silicon-based substrate.

22. (currently amended) A component, comprising:

a silicon-based substrate; and

a diffusion barrier coating disposed on said substrate, wherein said diffusion barrier coating comprises:

an isolation layer consisting of Ta_2O_5 , Ta_5Si_3 , $TaSi_2$, $MoSi_2$, and Mo_5Si_3 disposed on said silicon-based substrate;

a first oxygen barrier layer disposed on said first isolation layer; and
a second oxygen barrier layer disposed on said first oxygen barrier layer,
wherein each of said first oxygen barrier layer and said second oxygen
barrier layer comprises silica or a silicate and provides a barrier to the diffusion of
oxygen therethrough; and

an environmental barrier coating disposed on said diffusion barrier coating, said environmental barrier coating comprising at least about 50 mole % AlTaO₄.

23. (canceled).

- 24. (original) The component of claim 22, wherein each of said first oxygen barrier layer and said second oxygen barrier layer comprise a material selected from the group consisting of SiO₂, SeSiO₅, and Se₂Si₂O₇.
 - (canceled).
 - (currently amended) The component of claim [[25]]22, further comprising:
 a thermal barrier coating disposed on said environmental barrier coating.
- (currently amended) A method for making a component, the method comprising:
 - a) providing a silicon-based substrate;
- b) forming a first isolation layer selected from the group consisting Ta₂O₅, Ta₅Si₅,
 TaSi₂, MoSi₂, and Mo₅Si₃ on said silicon-based substrate;

Appl. No. 10/644,523 Reply to Office Action of February 7, 2007

c) forming a first oxygen barrier layer on said first isolation layer; and

d) forming a second isolation layer on said first oxygen barrier layer, the second isolation layer comprising a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, and Mo₅Si₃,

wherein said first isolation layer isolates said oxygen barrier layer from said silicon-based substrate, and

wherein said first isolation layer is inert to said silicon-based substrate; and
e) forming an environmental barrier coating on said second isolation layer,
wherein said second isolation layer provides a barrier to the diffusion of
constituents of said environmental barrier coating into said first oxygen barrier layer.

- 28. (canceled).
- (original) The method of claim 27, wherein said first oxygen barrier layer provides a barrier to the diffusion of oxygen therethrough.
- 30. (original) The method of claim 27, wherein said first isolation layer provides a barrier to the diffusion of constituents of said silicon-based substrate into said first oxygen barrier layer.
 - (canceled).
 - (currently amended) The method of claim [[31]]27, further comprising:
 f) forming a thermal barrier coating on said environmental barrier coating.
- 33. (original) The method of claim 27, wherein said first isolation layer, said oxygen barrier layer, and said second isolation layer are deposited via a process selected from the group consisting of plasma spray coating, dip coating, sol-gel coating, chemical vapor deposition, physical vapor deposition, and electron beam physical vapor deposition.

- 34. (original) The method of claim 27, wherein said step b) and said step d) respectively comprise depositing said first isolation layer and said second isolation layer via chemical vapor deposition.
- (original) The method of claim 27, further comprising:
 g) sequentially forming at least one additional oxygen barrier layer and at least one additional isolation layer on said second isolation layer.
- 36. (previously presented) A method for making a component, the method comprising:
 - a) providing a silicon-based substrate;
 - b) forming a first isolation layer on said silicon-based substrate;
 - c) forming a first oxygen barrier layer on said first isolation layer;
 - d) forming a second isolation layer on said first oxygen barrier layer; and
 - e) forming an environmental barrier coating on said second isolation layer, wherein said first oxygen barrier layer comprises silicate glass, and

wherein said first isolation layer and said second isolation layer each comprise a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, and Mo₅Si₃.

- (original) The method of claim 36, further comprising:
 f) prior to said step e), forming a second oxygen barrier layer on said second isolation layer; and
- g) prior to said step e), forming a third isolation layer on said second oxygen barrier layer.
- 38. (currently amended) A method for making a component, the method comprising:
 - a) providing a silicon-based substrate;
- b) forming a first isolation layer on said silicon-based substrate, the first isolation $\underline{layer\ consisting\ essentially\ of\ Si_3N_d;\ and}$

c) forming a second isolation layer on said first isolation layer, said second isolation layer consisting essentially of Ta2O5;[[,]] and

wherein said first isolation layer consists essentially of Si₂N₄ and said second isolation layer consists essentially of Ta₂O₅

d) reacting the first isolation layer with the second isolation layer to form, in situ, an oxygen barrier layer between said first isolation layer and said second isolation layer.

39. (canceled).

- 40. (currently amended) The method of claim [[39]] <u>38</u>, wherein said step d) is performed during service conditions of said component.
- 41. (previously presented)A method for making a component, the method comprising:
 - a) providing a silicon-based substrate;
 - b) forming an isolation layer on said silicon-based substrate;
 - c) forming a first oxygen barrier layer on said isolation layer; and
 - d) forming a second oxygen barrier layer on said first oxygen barrier layer,

wherein said isolation layer isolates said oxygen barrier layer from said silicon-

based substrate,

wherein said isolation layer is inert to said silicon-based substrate, and wherein said isolation layer comprises a material selected from the group consisting of Ta₂O₅, Ta₅Si₃, TaSi₂, MoSi₂, and Mo₅Si₃, and wherein said first and second oxygen barrier layers comprise silica or a silicate.

(canceled)

43. (original) The method of claim 41, wherein said first oxygen barrier layer and said second oxygen barrier layer each comprise a material selected from the group consisting of SiO₂, SeSiO₅, and Se₂Si₂O₇.

- 44. (original) The method of claim 41, wherein said isolation layer provides a barrier to the diffusion of constituents of said silicon-based substrate into said first oxygen barrier layer.
 - 45. (original) The method of claim 41, further comprising:e) forming an environmental barrier coating on said second oxygen barrier layer.
 - 46. (original) The method of claim 45, further comprising:f) forming a thermal barrier coating on said environmental barrier coating.
- 47. (original) The method of claim 41, wherein said isolation layer, said first oxygen barrier layer, and said second oxygen barrier layer are deposited via a process selected from the group consisting of plasma spray coating, dip coating, sol-gel coating, chemical vapor deposition, physical vapor deposition, and electron beam physical vapor deposition.
- 48. (original) The method of claim 41, further comprising:

 g) forming at least one additional oxygen barrier layer on said second oxygen barrier layer.